Diverse produse (conform descrierii)

I.D.: 6722757

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Descriere: The University of Sheffield is out to tender on behalf of the Department of Materials Science and Engineering for a Focused Ion Beam Facility.We seek to purchase a dual beam Focused Ion Beam – Scanning Electron Microscope Instrument. The instrument will be used for the investigation of a wide range of materials, including polymers, metals, ceramics, glasses, composites, semiconductors, nanomaterials, nanostructures and coatings. The instrument will be used for:a) the ultra-high resolution investigation of the surfaces of materials using both secondary electron (ISE and ESE) and back scattered electron signals;b) the ability to examine material structure with minimal electron beam damage;c) the preparation of the highest quality samples for transmission electron microscopy with the ability to undertake high resolution TEM without further sample preparation;d) to undertake STEM experiments directly in the instrument;e) to undertake dynamic nanoscale experiments within the microscope;f) to be able to lithographically ion mill surface structures such as nano-pillars etc.;g) to have the option of undertaking several different analytical techniques in the microscope;h) to enable the investigation of 3D materials volumes through iterative cutting and imaging of sample surfaces.For the purposes of this procurement our requirements have been divided into 3 lots as follows:— Lot 1 — Focused Ion Beam Scanning Electron Microscope (FIB SEM) system,— Lot 2 — Cooling system for FIB SEM,— Lot 3 — Energy Dispersive spectroscopy system for FIB SEM.Suppliers are welcome to tender for 1, 2 or all Lots.The closing date for return of tenders is Friday 10.7.2015 at 12 noon (UK time)Suppliers must register on the University"s e-tendering portal in order to access the tender documents and submit their responses.https://www.in-tendhost.co.uk/sheffield